

ABSTRACT OF THE DISCLOSURE

This invention provides an electron source manufacturing apparatus and manufacturing method which facilitate downsizing and operation and are suitable
5 for mass production. The electron source manufacturing apparatus includes a support which supports a substrate having conductors formed on it and has a means for adjusting the temperature of the substrate, a vessel which has a gas inlet port and gas exhaust port and
10 covers a partial region on the surface of the substrate, an unit for introducing and exhausting gas into and from the vessel, and an unit for applying a voltage to the conductors. The support has a groove.

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